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## MOEMS: Micro-Optical MEMS

Guest Editors:

**Dr. Nelson Sepulveda**

Department of Electrical and  
Computer Engineering, Michigan  
State University, East Lansing,  
MI 48824-1226, USA

nelsons@egr.msu.edu

**Dr. Jing Wang**

Department of Electrical  
Engineering, University of South  
Florida, Tampa, Florida 33620,  
USA

jingw@eng.usf.edu

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### Message from the Guest Editors

Optical microelectromechanical systems (MEMS), microoptoelectromechanical systems (MOEMS), or optical microsystems are integrated devices or systems that interact with light through actuation or sensing at a micro or millimeter scale. The multidisciplinary nature of the field has allowed for the collaboration of researchers with a very diverse background and enabled a rapid technological growth that has resulted in enormous commercial success in imaging, laser scanners, and optical communications.

In this Special Issue, the current state of this exciting research field will be presented, covering a wide range of topics, including but not limited to:

- Optical scanners and micromirrors; Optical MEMS transducers; Photothermal transducers;
- Micro-optical systems for imaging; Optical communications devices; Diffractive MEMS;
- Optical beam steering; Wavelength selective switch (WSS); Tunable filters;
- Miniature LiDAR and virtual reality/augmented reality (VR/AR); Variable optical attenuators;
- Adaptive and tunable optics; Optical devices for wavelength division multiplexing (WDM);
- Optical waveguides; Diffractive gratings; Optofluidics; Spatial light modulators;
- Microspectrometers; Microphotonics; Microspectrometers; Cavity optomechanics.



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